

**SEC.584**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re PATENT APPLICATION of

Ki-sang KIM et al.

Group Art Unit: 1763

Serial No.: 09/237,229

Examiner: Lund, J.

Filed: January 26, 1999

For: MULTI-CHAMBER SYSTEM HAVING COMPACT INSTALLATION SET-UP FOR  
AN ETCHING FACILITY FOR SEMICONDUCTOR DEVICE MANUFACTURING

**SUPPLEMENTAL PRELIMINARY AMENDMENT**

Honorable Assistant Commission of Patents and Trademarks,  
Washington, D.C. 20231

Date: August 7, 2000

Sir:

Preliminary to the examination of the above-identified application, please enter  
the following amendments and remarks.

**In the claims:**

Please add the following claims:

33. A method of manufacturing semiconductor devices in a multi-chamber  
system of an etching facility, comprising:
- mounting on a cassette stage a cassette that has wafers stacked thereon;
  - maintaining a transfer path that is adjacent to the cassette stage at atmospheric  
pressure, the transfer path providing space for transportation of wafers;